

Vacuum Probing System Solutions

- Manual, Semiautomatic & Fully Automatic Versions
 - Die, modules, partial wafers and whole wafers up to 300 mm
- Applications: MEMS, High Voltage up to 10 KV and others
- Single or Multi-Purpose configurations from R&D to Production
- Vacuum levels to 10^{-5} torr – contact the factory for higher vacuum levels
- Thermal Systems from -60 C to 300 C
- Manipulators – Programmable – local and remote control
- Probe Arms – coaxial, triaxial, kelvin, High Frequency, High Power and more
- Probe Tips, Probe Cards, Wedges,
- Black Bodies, Motion Analyzers, IR Cameras and more
- Integrated Solutions with Test Instrumentation
- Modular PS4L Hardware & Software Architecture

